



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of:
Mei, et al.

Serial No. 10/064,156

Filed: June 14, 2002

For: MODIFIED
PHOTOLITHOGRAPHY MOVEMENT
SYSTEM

§ Group Art Unit: 2183
§
§ Examiner: Unknown
§
§
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INFORMATION DISCLOSURE STATEMENT

Commissioner For Patents
Washington, D.C. 20231

Dear Sir:

In compliance with the duty of disclosure under 37 CFR §1.56, and in accordance with the practice under 37 CFR §1.97 and §1.98, the Examiner's attention is directed to the documents listed on the enclosed modified Form PTO-1449. No inference should be made that the cited references are in fact material, are in fact prior art, or that no better art exists. The cited patents are listed in numerical order and are not in any order based on their pertinence. Copies of the listed information are attached.

This Information Disclosure Statement is being filed within three months of the United States filing date or before the mailing date of a first Office Action on the merits. No certification or fee is required (37 CFR §1.97(b)).

The Commissioner is hereby authorized to charge any additional fees which may be required or credit any overpayment to Deposit Account 08-1394.

It is respectfully requested that the above information be considered by the Examiner and that a copy of the enclosed Form PTO-1449 be returned indicating that such information has been considered.

Respectfully submitted,

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Registration No. 42,044

Date: 2-4-03
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Certificate of Mailing

I hereby certify that this correspondence is being deposited with the United States Postal Service as first class mail in an envelope addressed to Commissioner For Patents, Washington, D.C. 20231 on 2.5.03.

B.E. Boyle

Printed Name

B.E. Boyle

Signature



U. S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE INFORMATION DISCLOSURE STATEMENT BY APPLICANT <i>(use as many sheets as necessary)</i>				<i>Complete if Known</i> Application Number 10/064,156 Filing Date June 14, 2002 Applicant(s) Mei, et al. Art Unit 2183 Examiner Name Unknown SHEET 1 OF 3 Attorney Docket Number 22397.324	
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U. S. PATENT DOCUMENTS				
Examiner's Initials	Cite No.	Document Number	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document
	AA	3,534,467	10/20/1970	B. Sachs, et al.
	AB	4,126,812	11/21/1978	Wakefield
	AC	4,744,047	05/10/1988	Okamoto, et al.
	AD	4,786,149	11/22/1988	Hoening, et al.
	AE	4,879,466	11/07/1989	Kitaguchi, et al.
	AF	5,049,901	09/17/1991	Gelbart
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	BC	5,870,176	02/09/1999	Sweatt, et al
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	BM	6,014,203	01/11/2000	Ohkawa
	BN	6,048,011	04/11/2000	Fruhling, et al.
	BO	6,052,517	04/18/2000	Matsunaga, et al.
	BP	6,061,118	05/09/2000	Takeda

Examiner Signature	Date Considered
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EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include a copy of this form with next communication to applicant.

In place of PTO-1445 Form 10 10 2003 03 PATENT AND TRADEMARK OFFICE INFORMATION DISCLOSURE STATEMENT BY APPLICANT <i>(use as many sheets as necessary)</i>		U. S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE	
		Complete if Known	
		Application Number	10/064,156
		Filing Date	June 14, 2002
		Applicant(s)	Mei, et al.
		Art Unit	2183
		Examiner Name	Unknown
SHEET	2	of	3
Attorney Docket Number 22397.324			

FOREIGN PATENT DOCUMENTS					
Examiner's Initials	Cite No.	Foreign Patent Document (Country Code - Number - Kind)	Publication Date MM-DD-YYYY	Patentee or Applicant of Cited Document	Translation Y/N
	CA	WO 9110170	07/11/1991	Manufacturing Sciences, Inc.	
	CB	0552953	07/28/1993	Mumola	

OTHER PRIOR ART		
Examiner's Initials	Cite No.	Include name of the author (in CAPITAL LETTERS), title of the article, title of the item, date, page(s); volume-issue number(s), publisher, city/country where published
	DA	"New Multi-EB Direct Write Concept for Maskless High Throughput", Canon SubMicron Focus, Volume 5, Summer 2000
	DB	Sandstrom and Odselius, "Large-Area High Quality Photomasks", Micronic Laser Systems, published by SPIE, Volume 2621, 1985, pgs. 312-318.
	DC	Singh-Gasson, Sangeet et al., "Maskless Fabrication of Light-Directed Oligonucleotide Microarrays Using a Digital Micromirror Array, Volume 17, No. 10, October 1999, pgs. 974-978.
	DD	Devitt, Terry, "Advanced May Put Gene Chip Technology on Scientists Desktops", http://www.biotech.wise.edu/Education/biotechnews/GeneChip.html , October 7, 1999